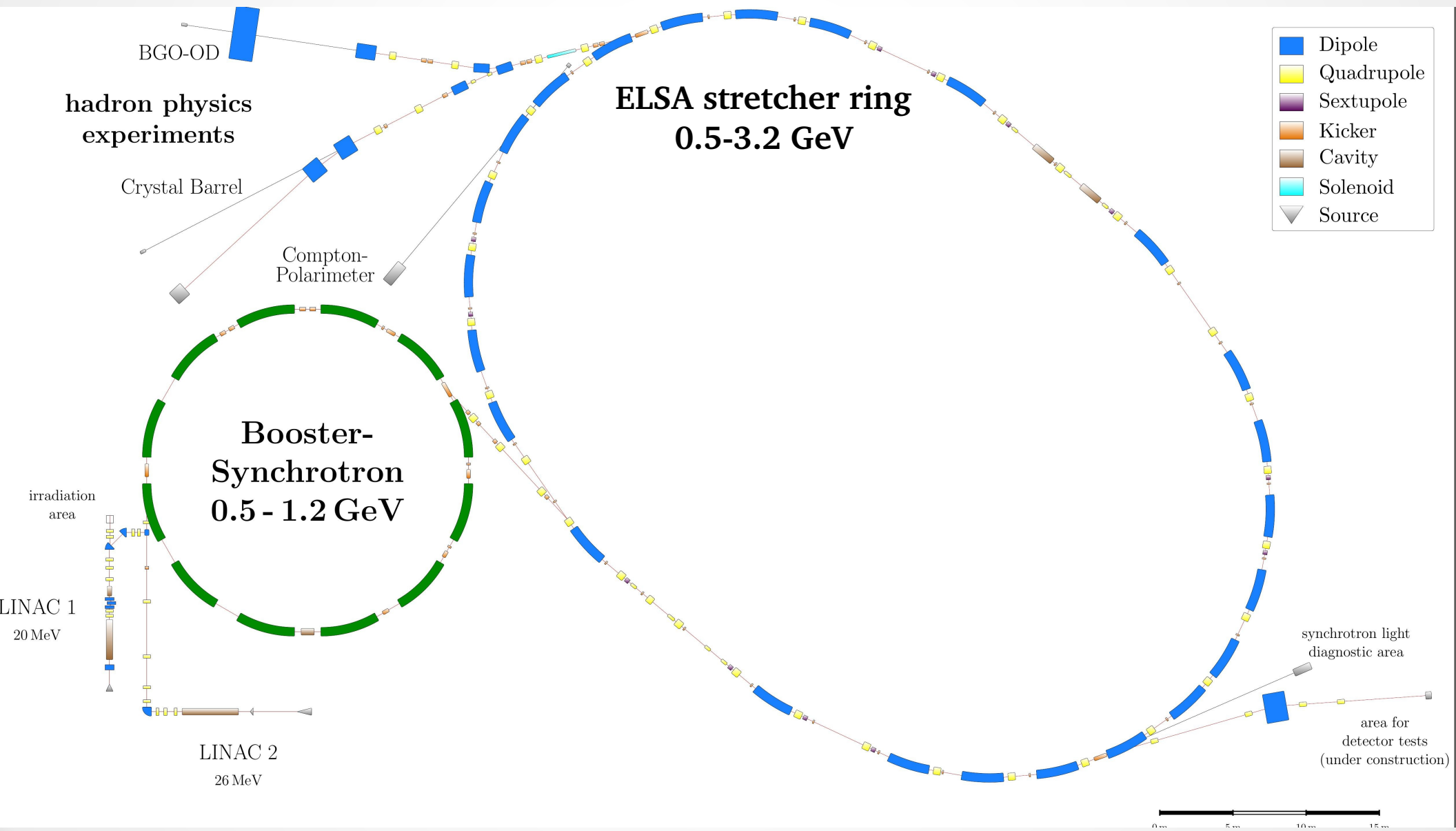


A Compton Polarimeter for ELSA

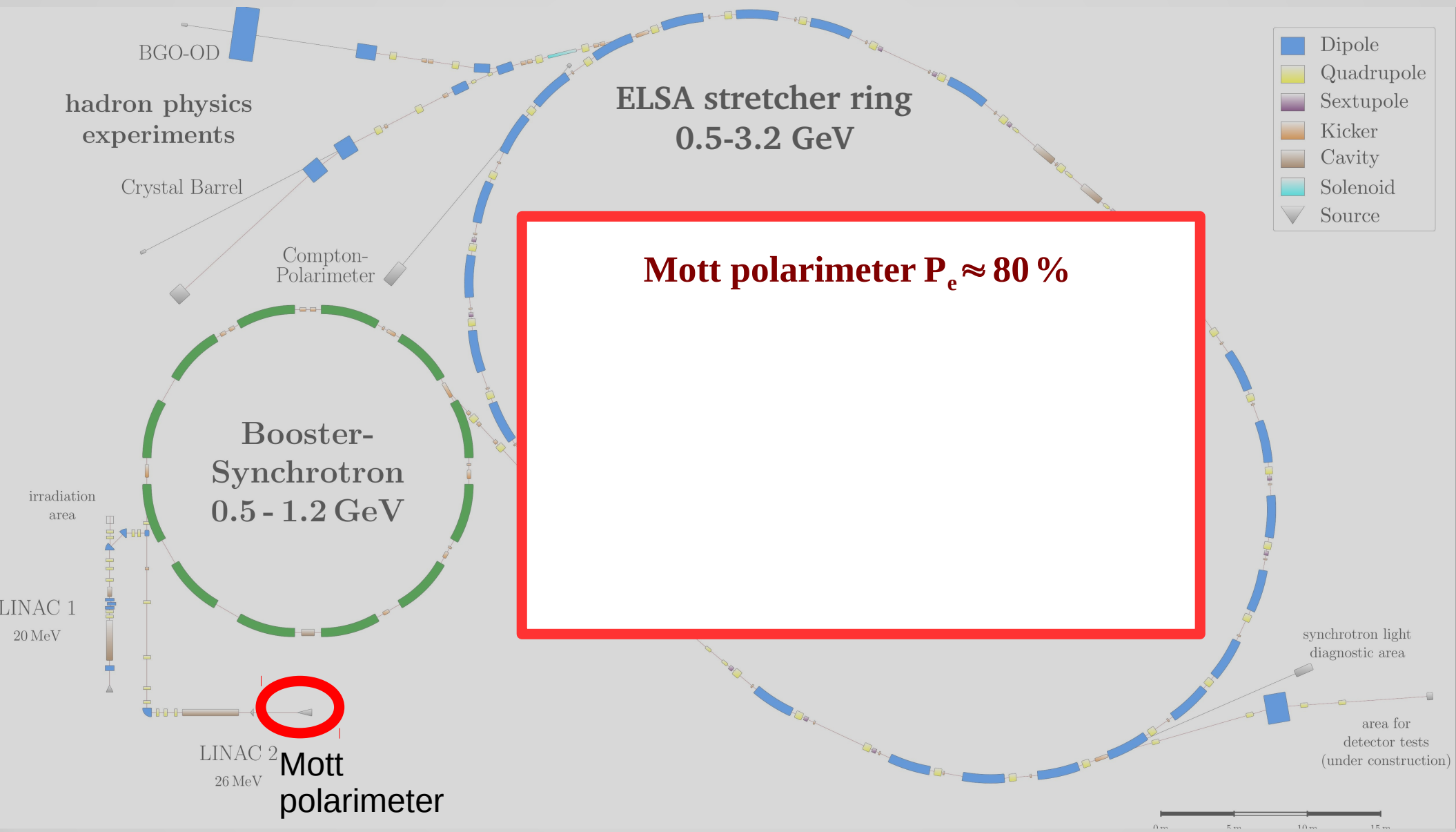
Rebecca Koop

*Physikalisches Institut
University of Bonn
Germany*

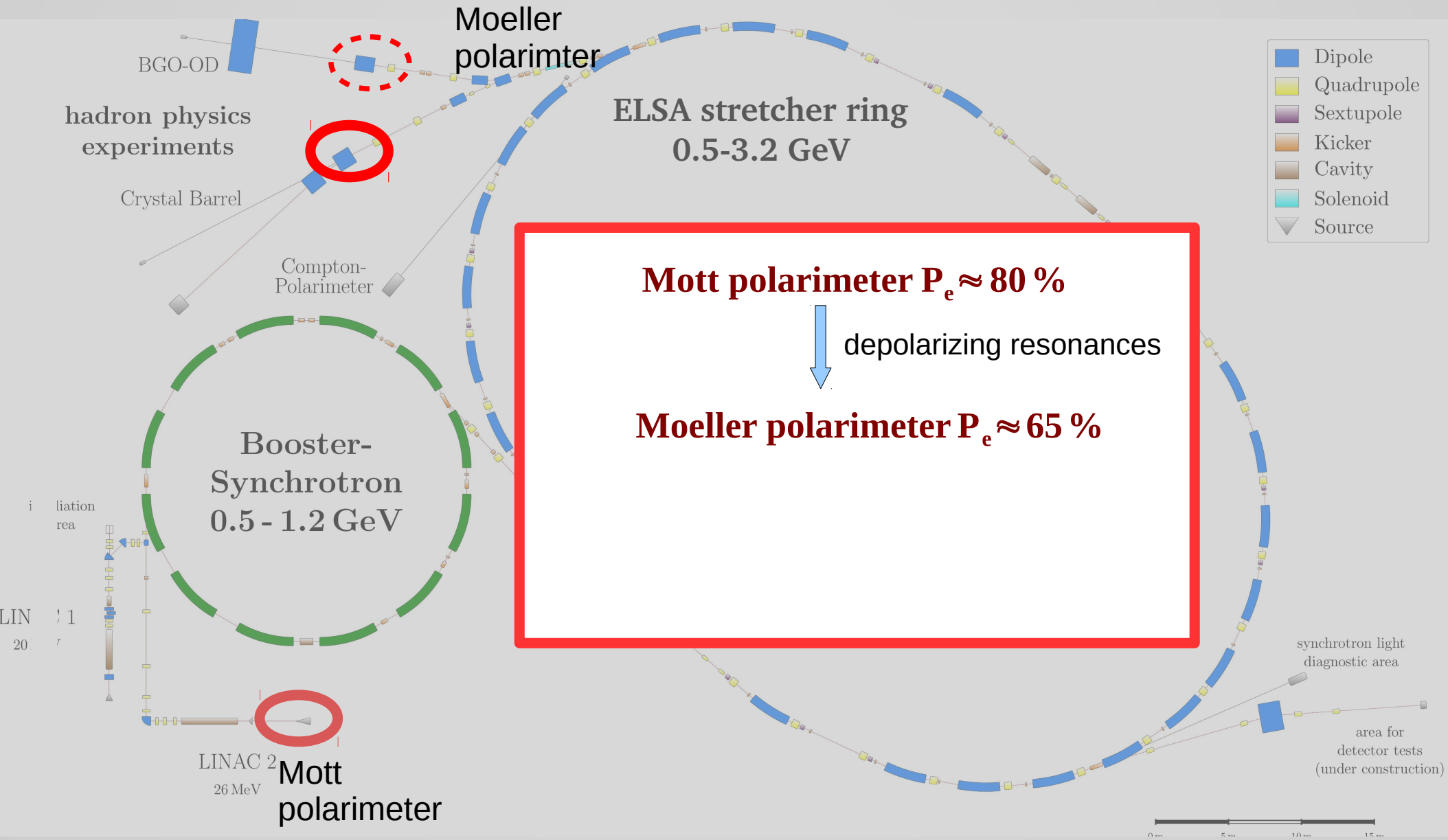
Electron Stretcher Facility ELSA



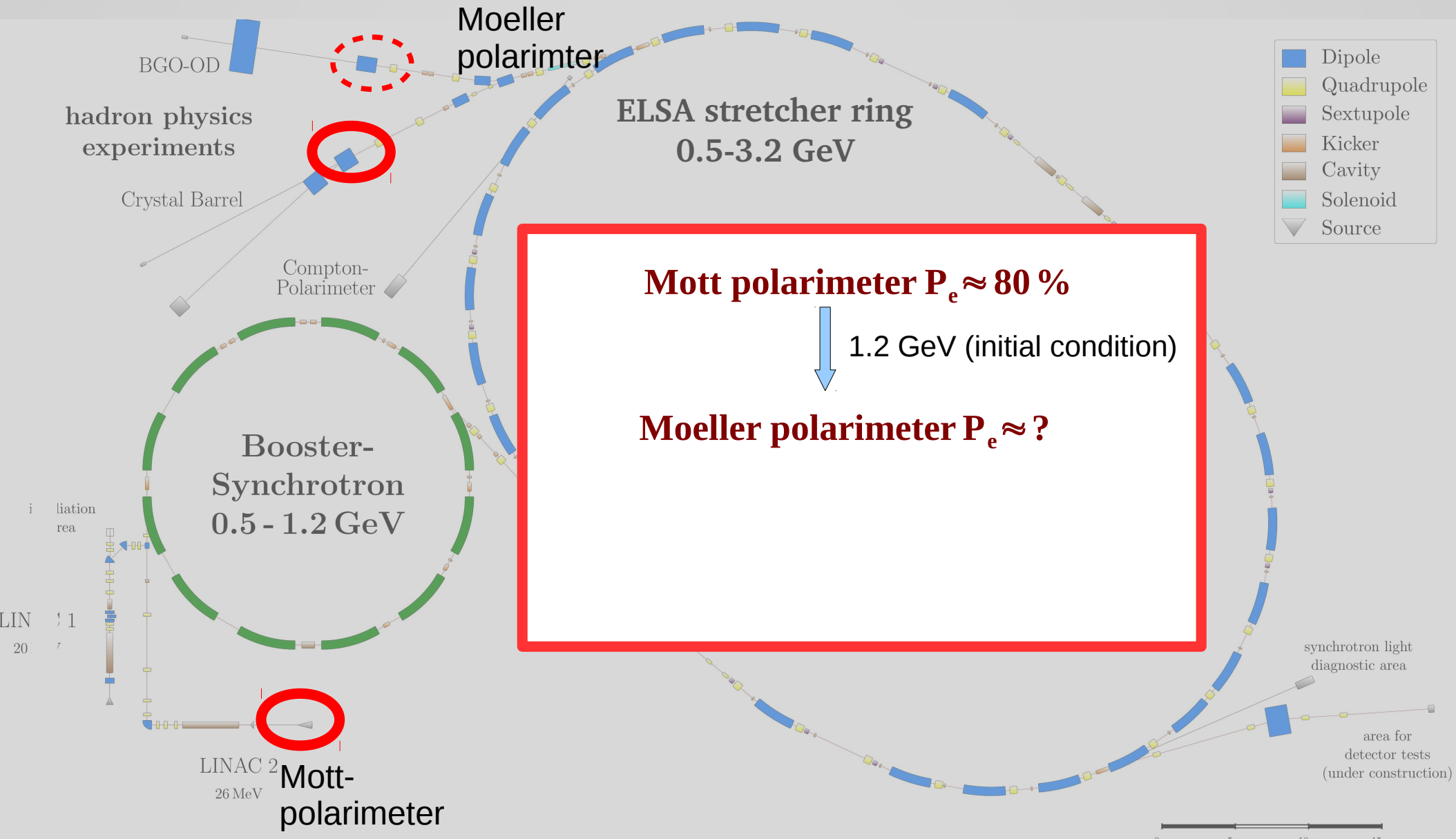
Motivation for Compton Polarimetry



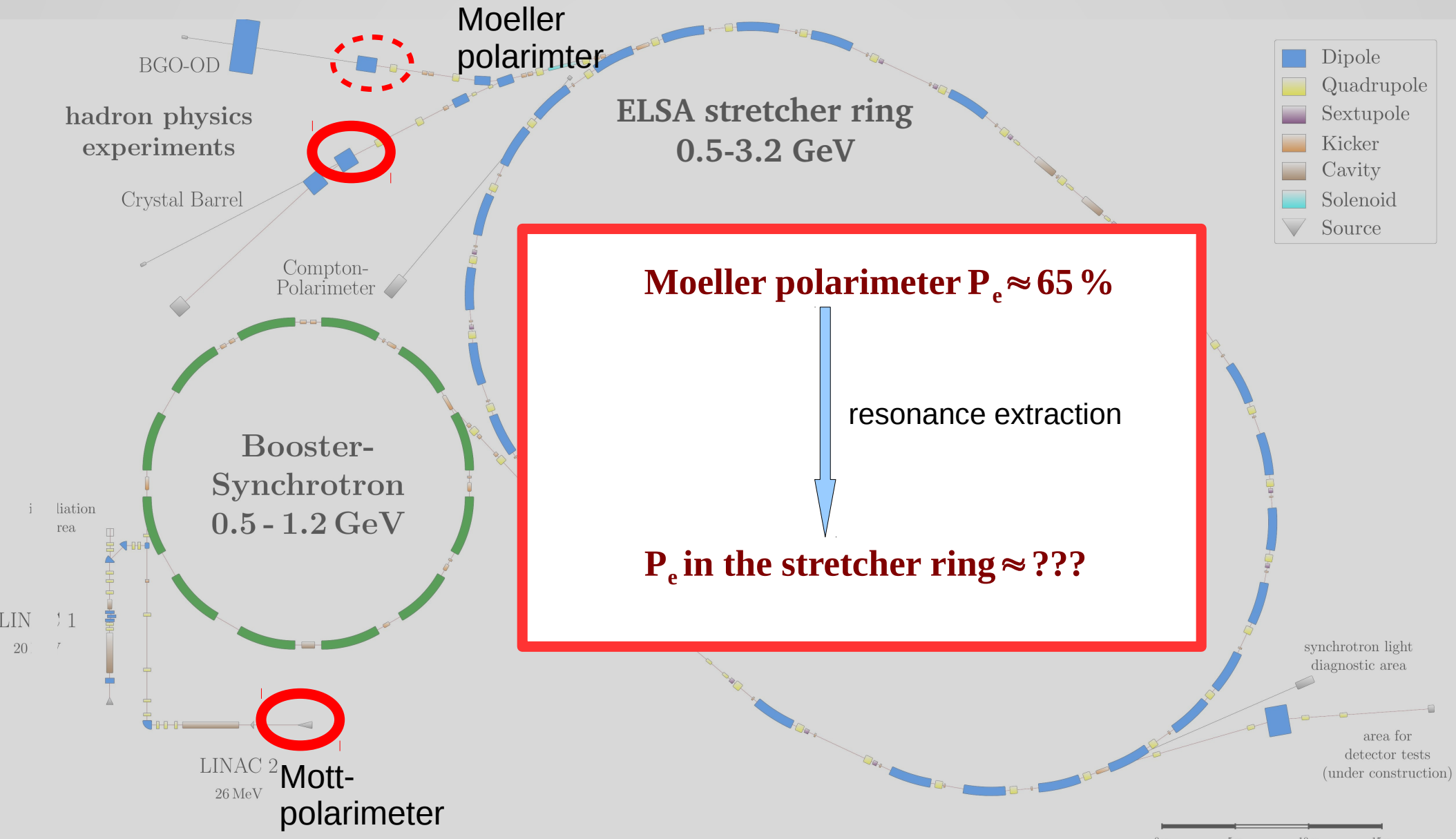
Motivation for Compton Polarimetry



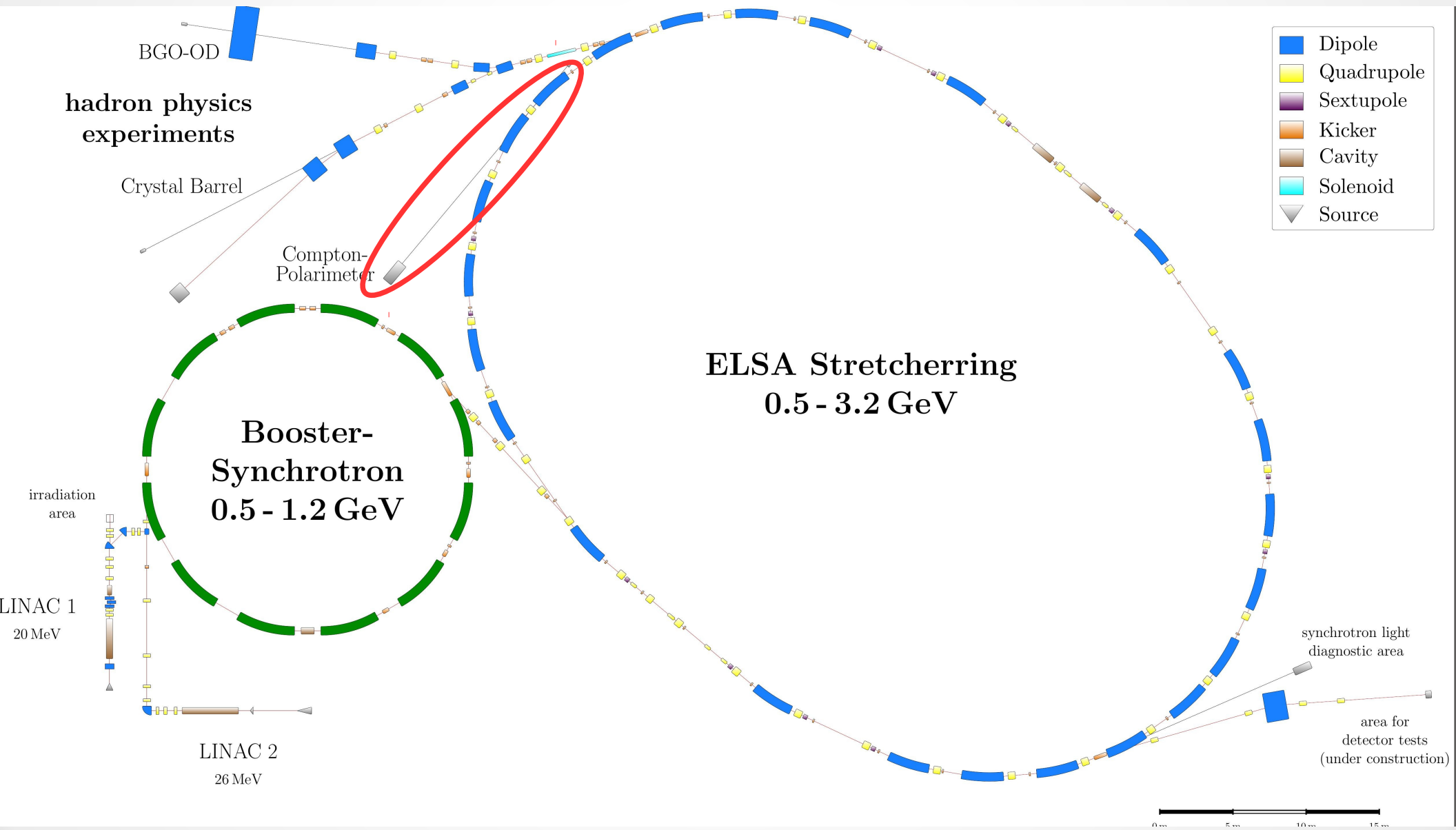
Motivation for Compton Polarimetry



Motivation for Compton Polarimetry



Motivation for Compton Polarimetry

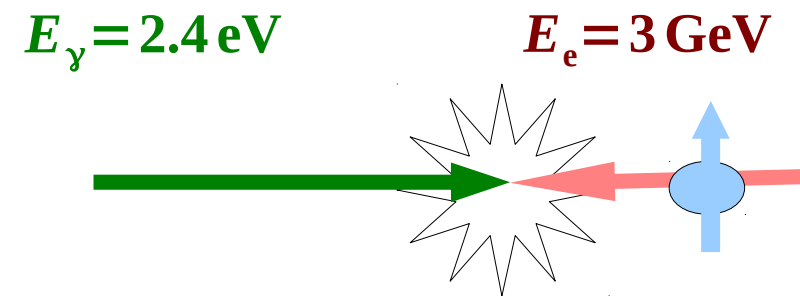


Compton-Scattering for Polarimetry

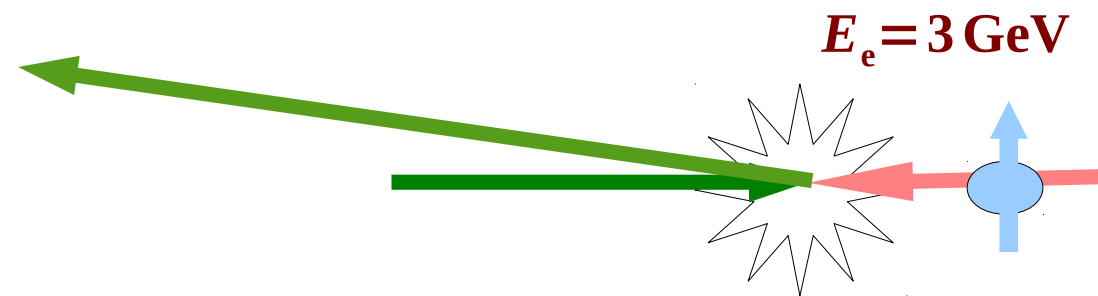
$$E_{\gamma} = 2.4 \text{ eV}$$



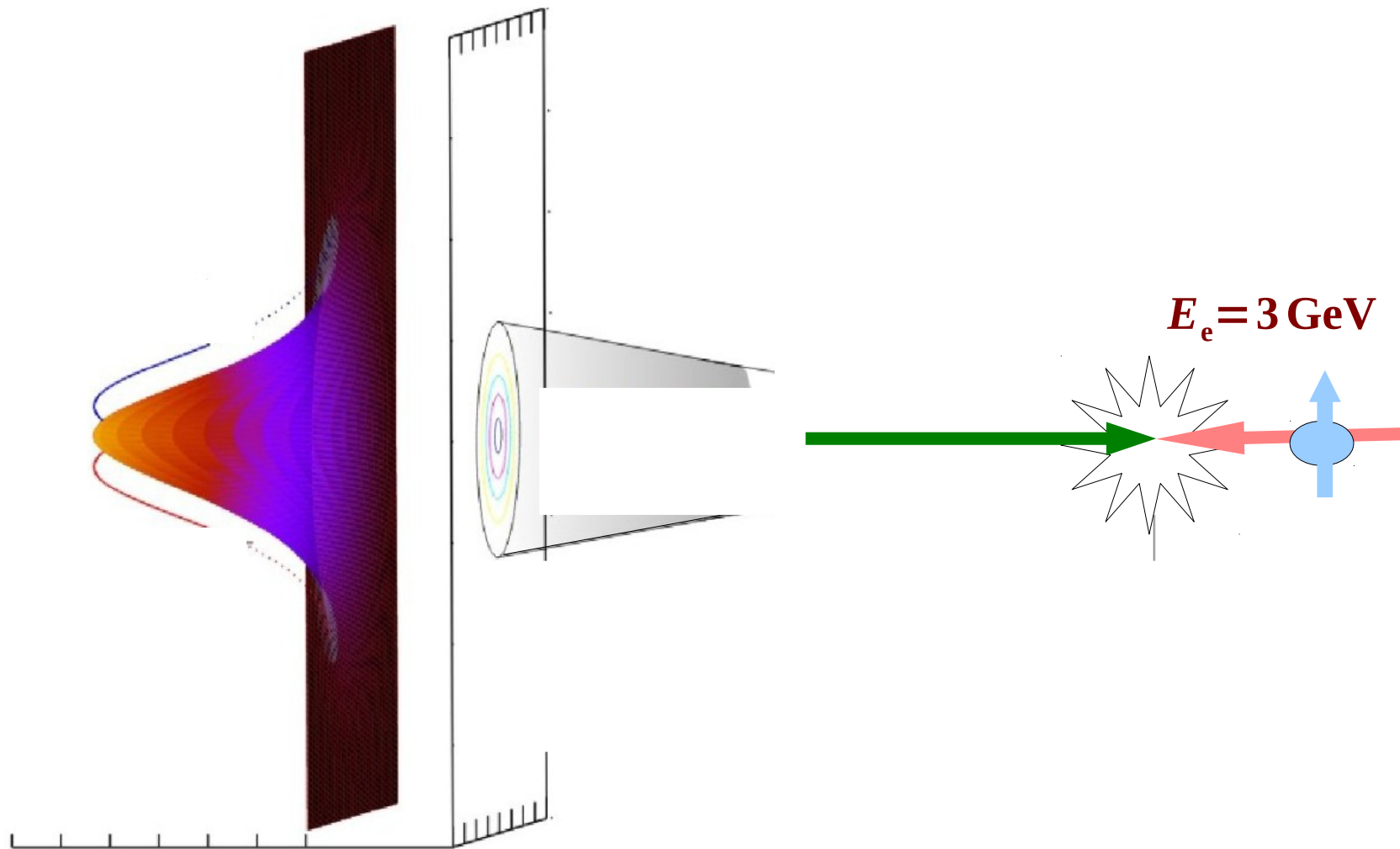
Compton-Scattering for Polarimetry



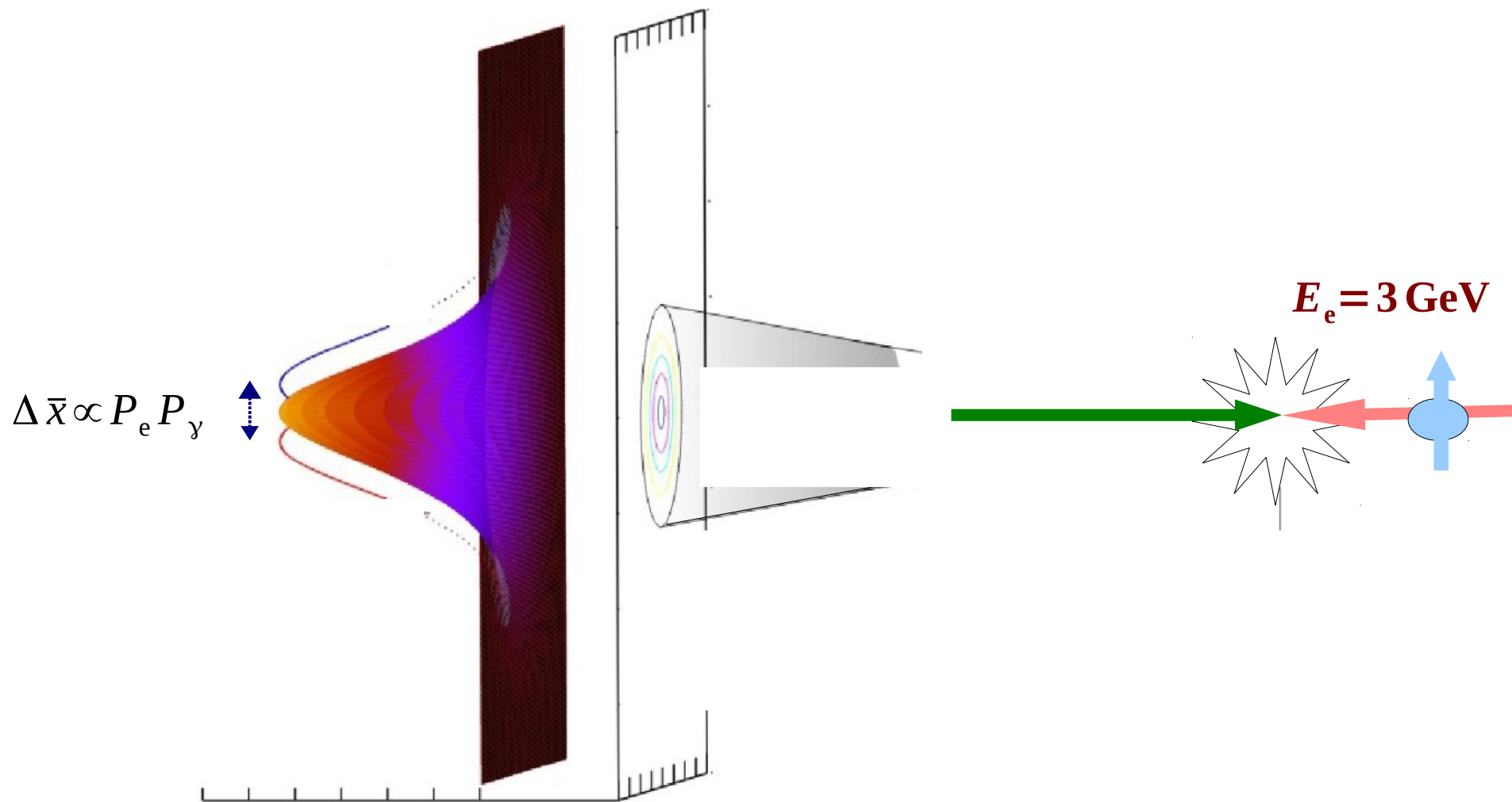
Compton-Scattering for Polarimetry



Compton-Scattering for Polarimetry

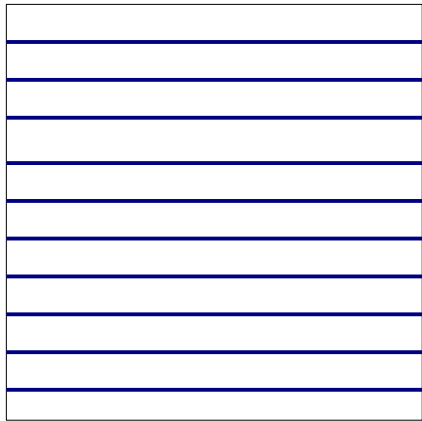


Compton-Scattering

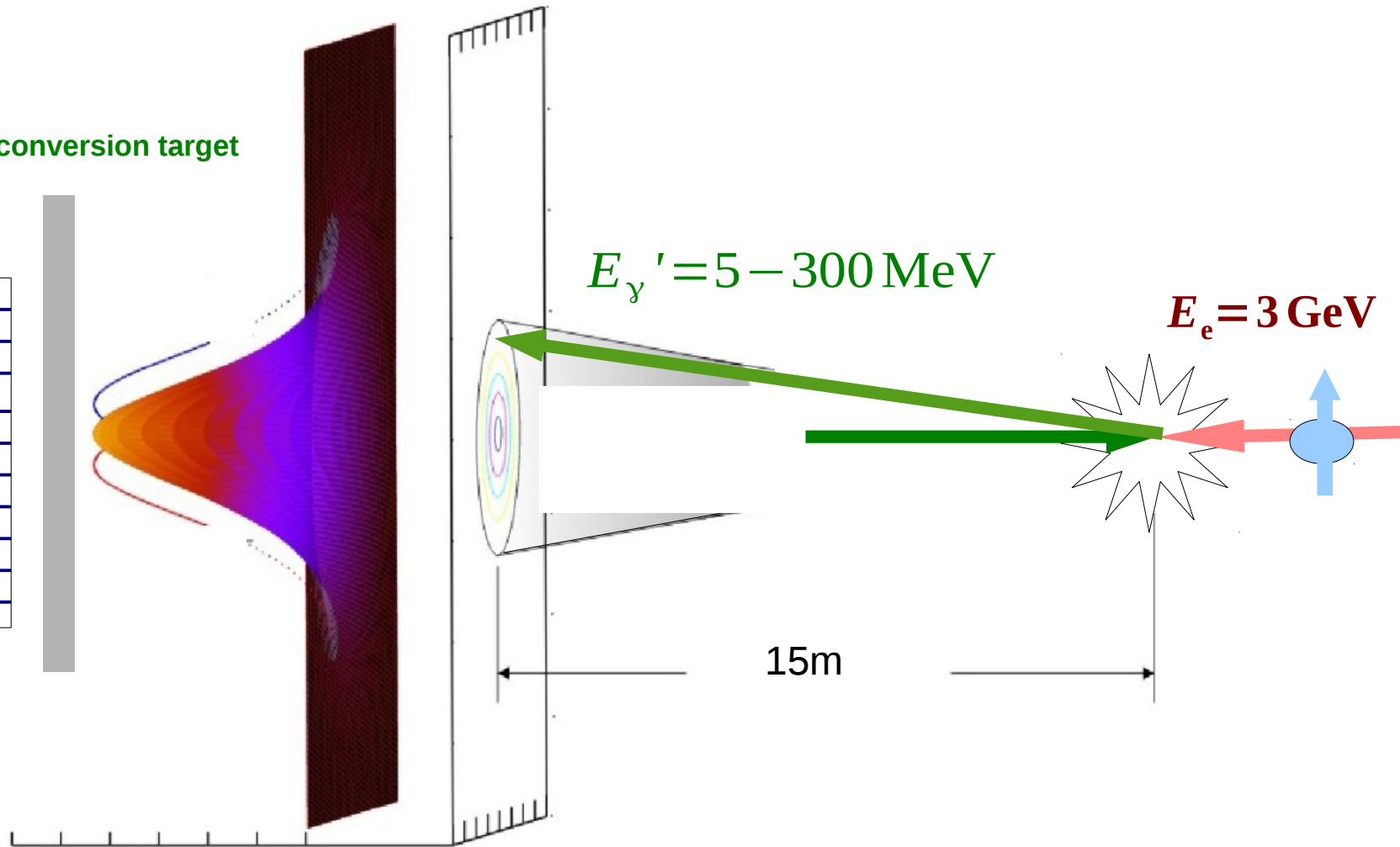


Compton-Scattering

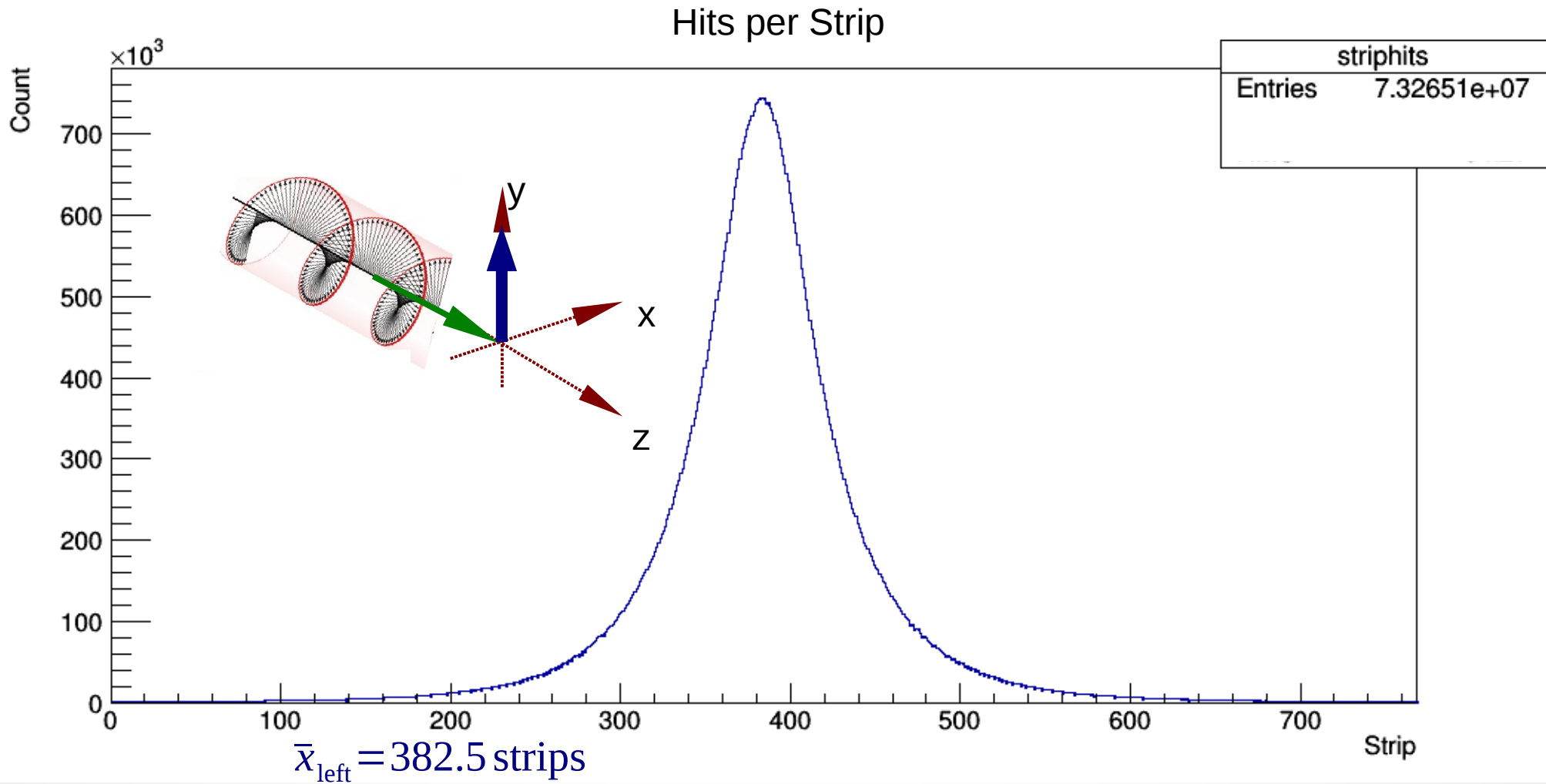
Lead conversion target



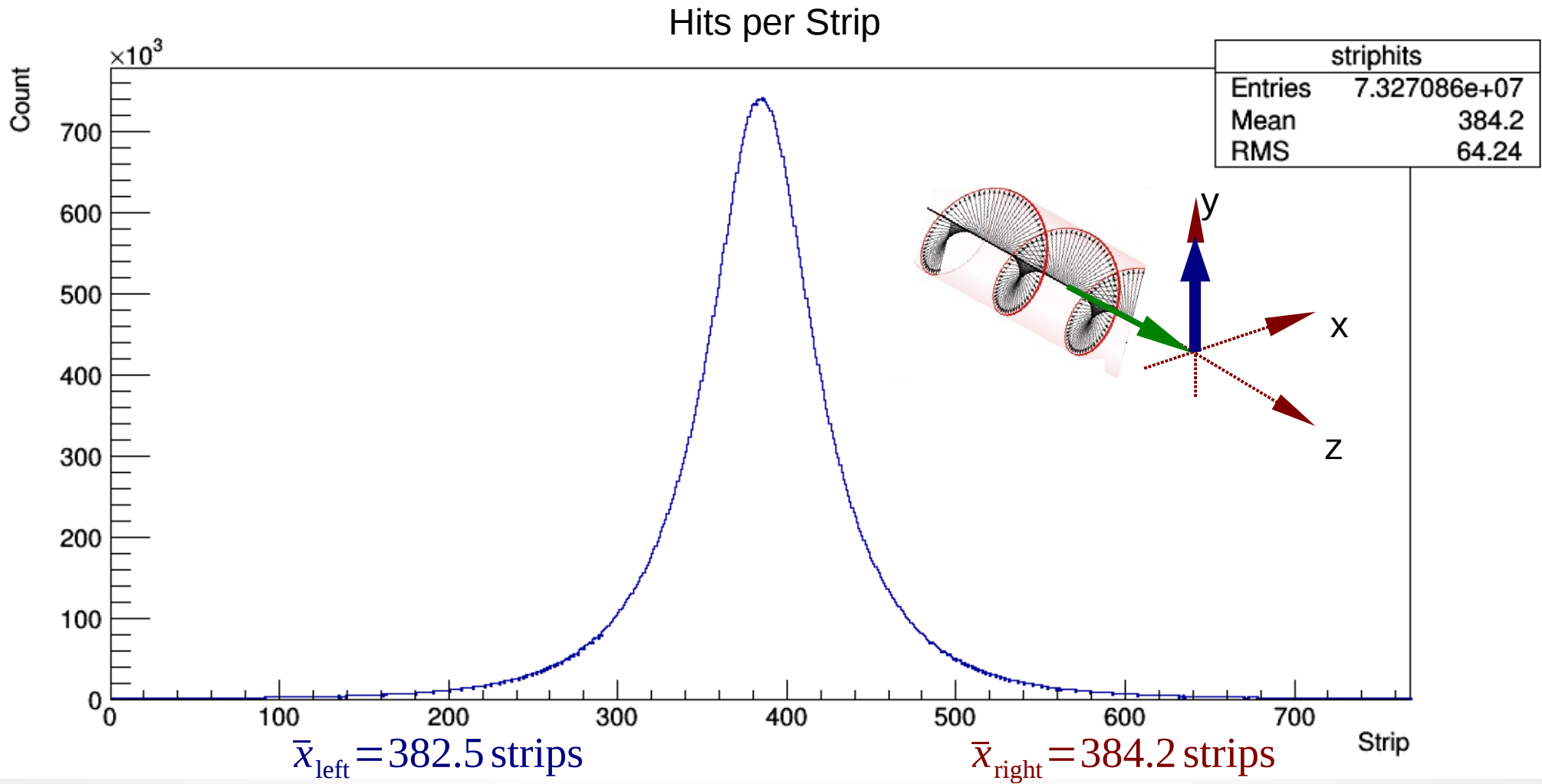
Silicon strip detector,
768 strips,
50 μ m pitch



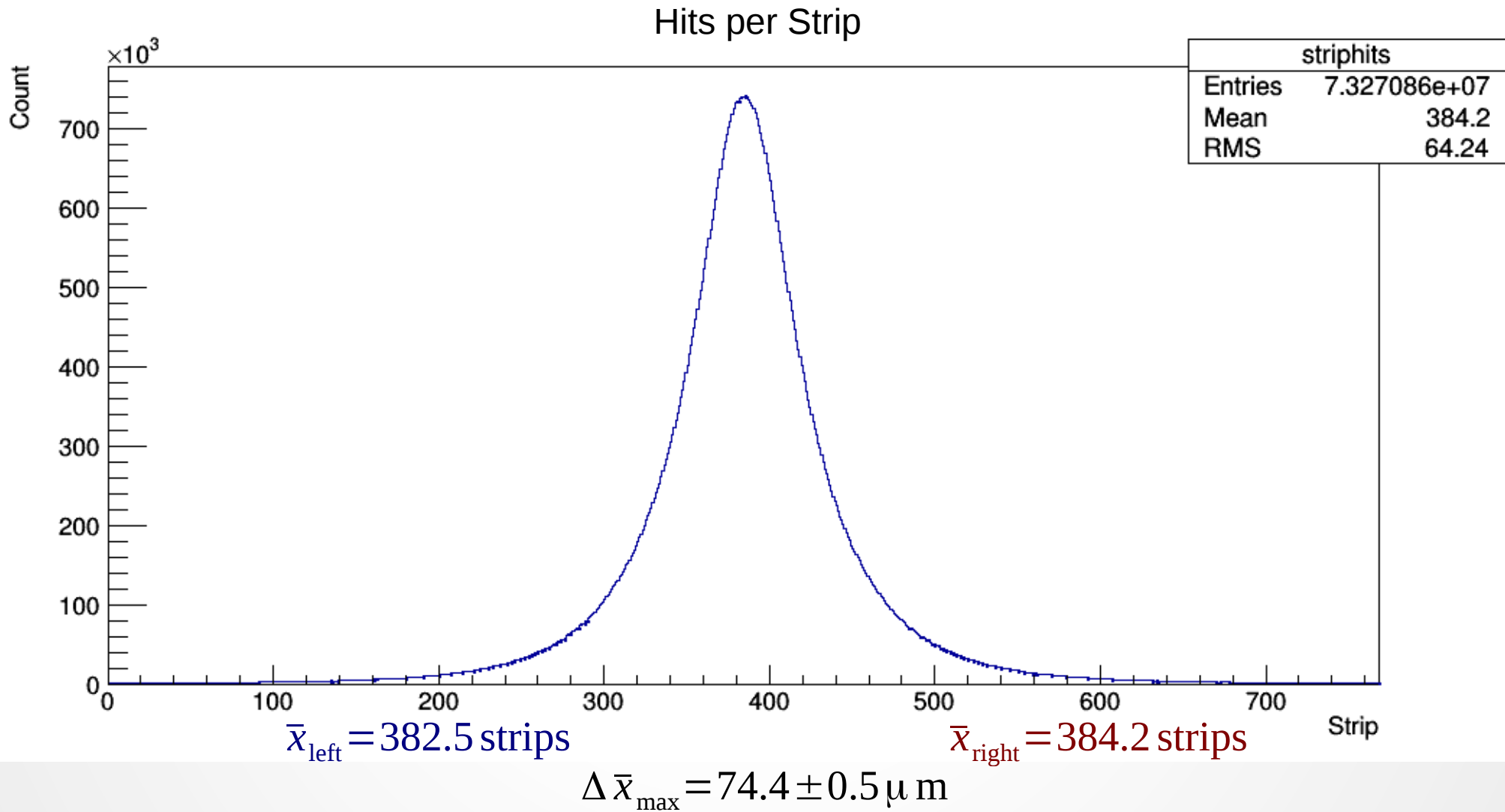
Geant4 Simulation



Geant4 Simulation

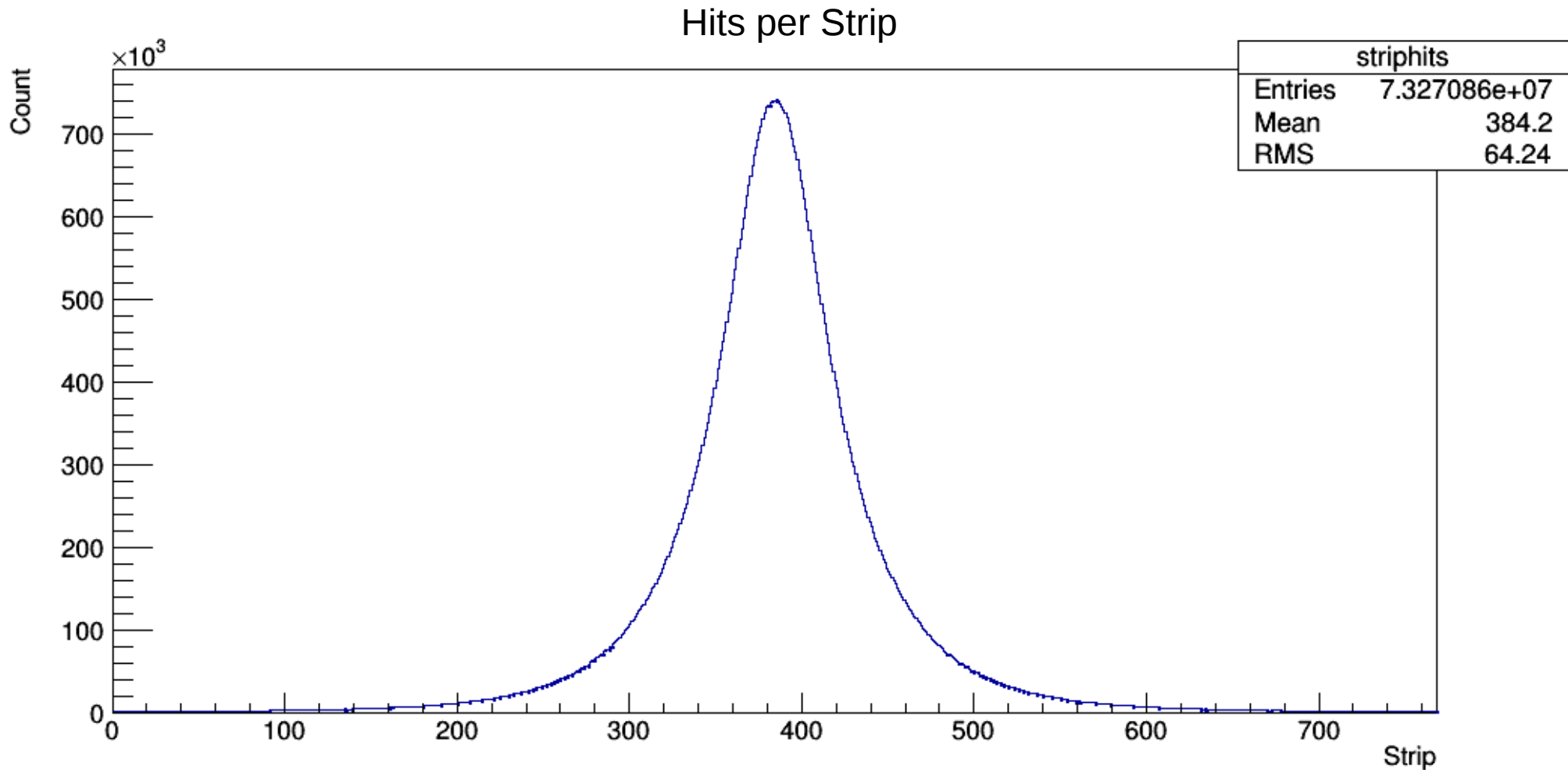


Geant4 Simulation



$$P_e = \frac{\Delta \bar{x}}{P_y \cdot 74.4 \mu\text{m}}$$

Geant4 Simulation

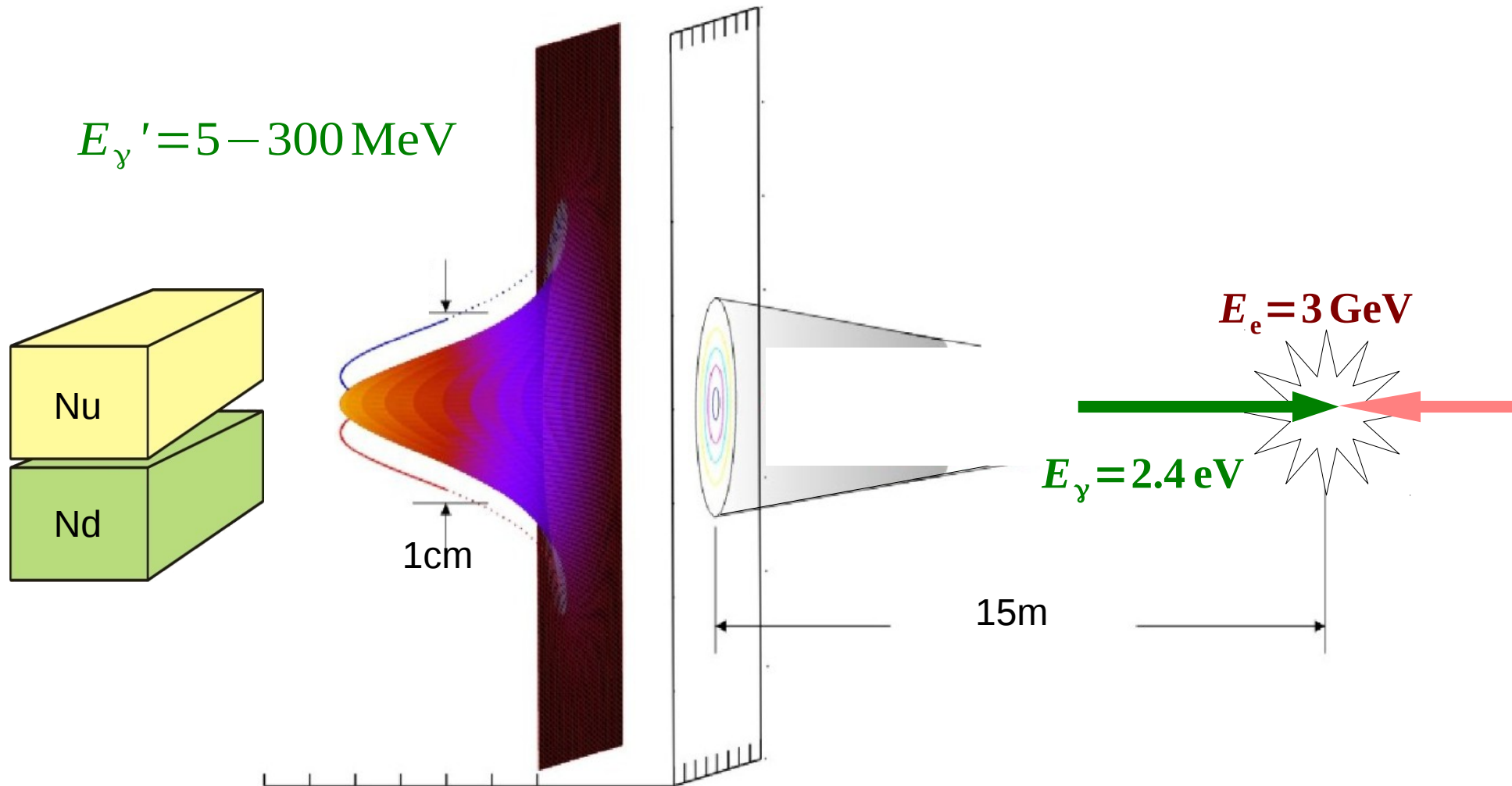


$$\Delta \bar{x}_{\max} = \Delta \bar{x}_{\max} (E, twiss)$$

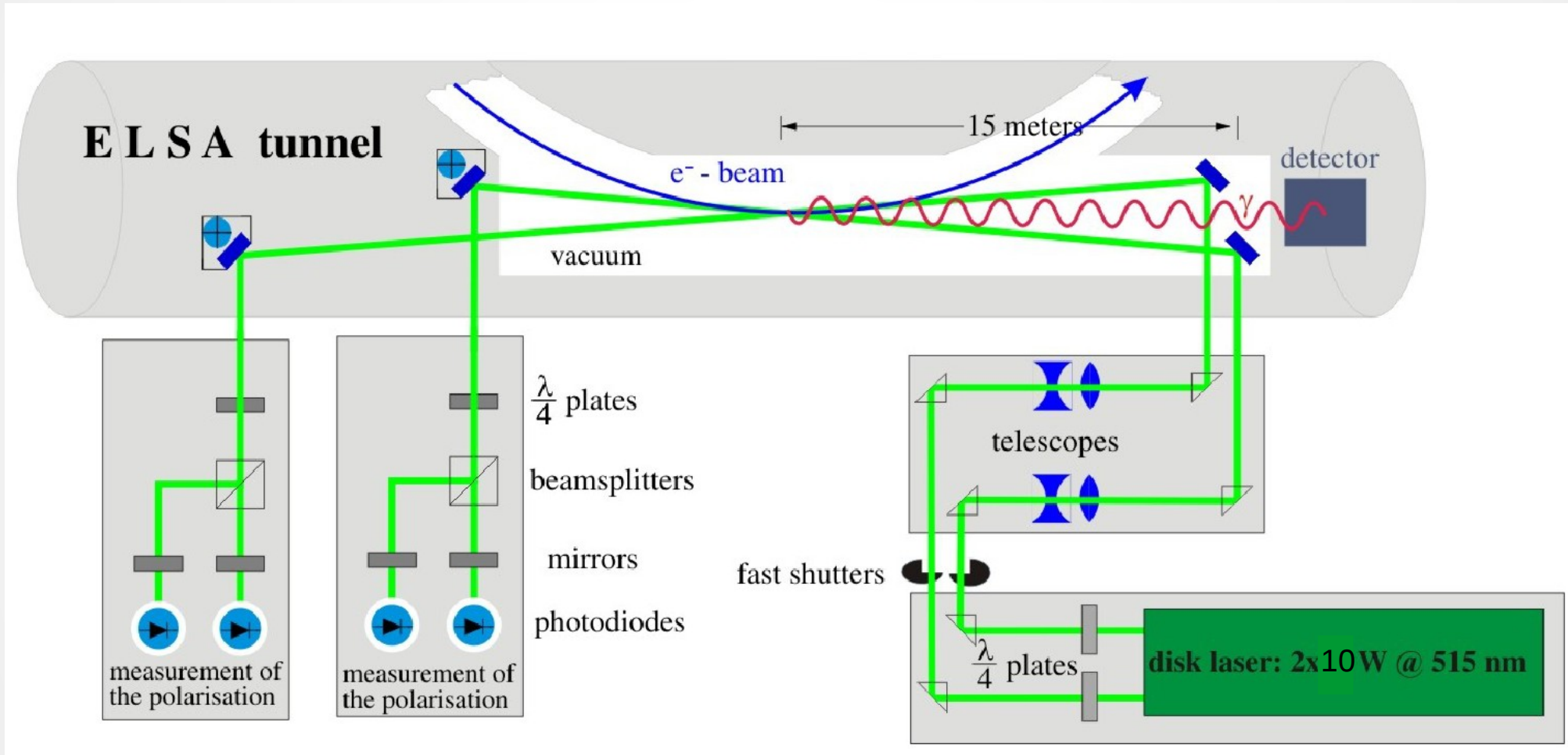
$$P_e = \frac{\Delta \bar{x}}{P_y \cdot 74.4 \mu\text{m}}$$

Calibrated with Sokolov-Ternov effect ¹⁷

Compton-Scattering



Compton System Components



$$P_e = \frac{\Delta \bar{x}}{P_y \cdot 74.4 \mu\text{m}}$$

Laser Beam Polarization and Position



$(99,97 \pm 0,01)\%$

Laser and Beamline

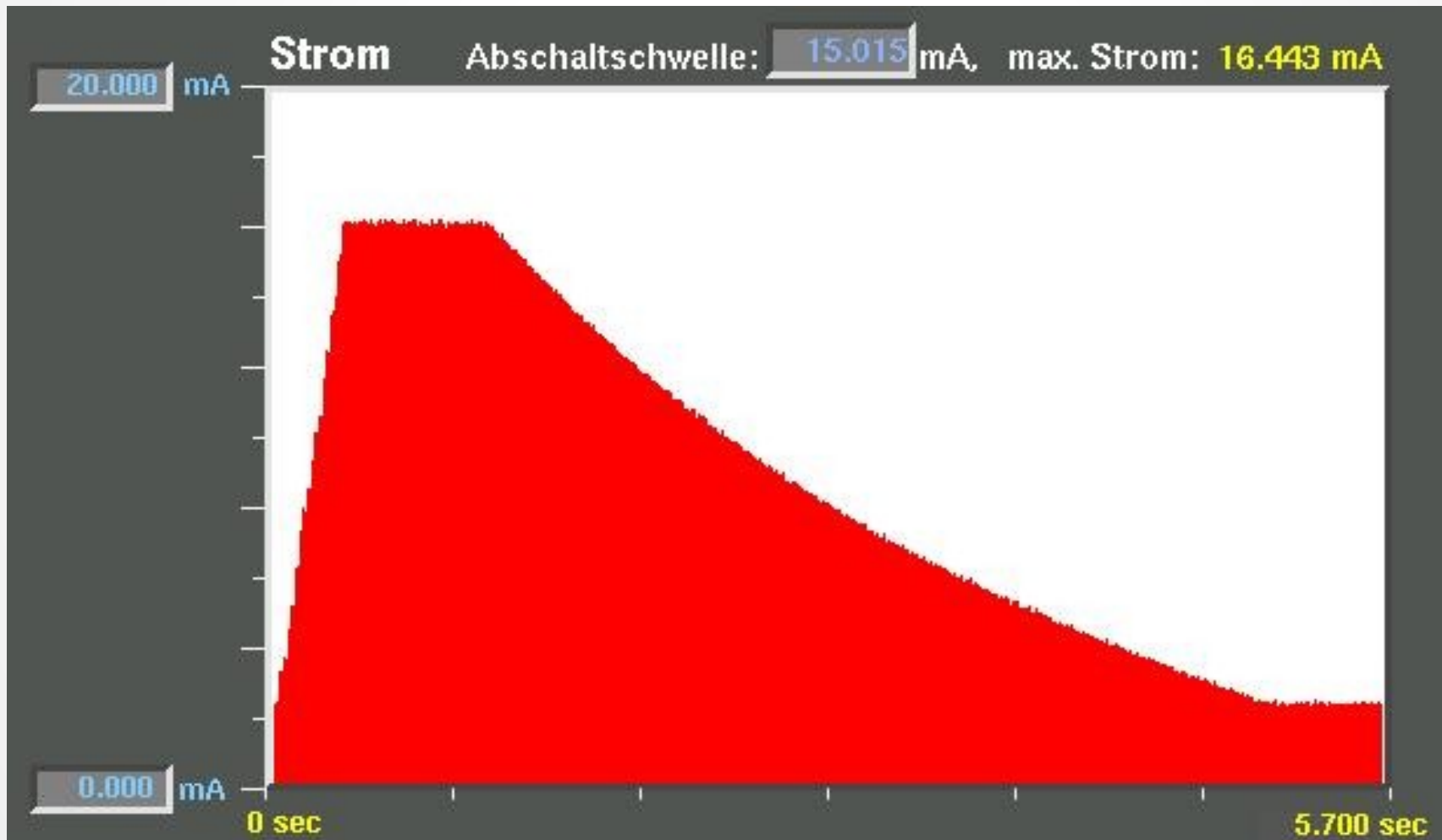


Detector System Considerations

- 50 μ m pitch
- 768 strips
- Rate acceptance of 1 MHz

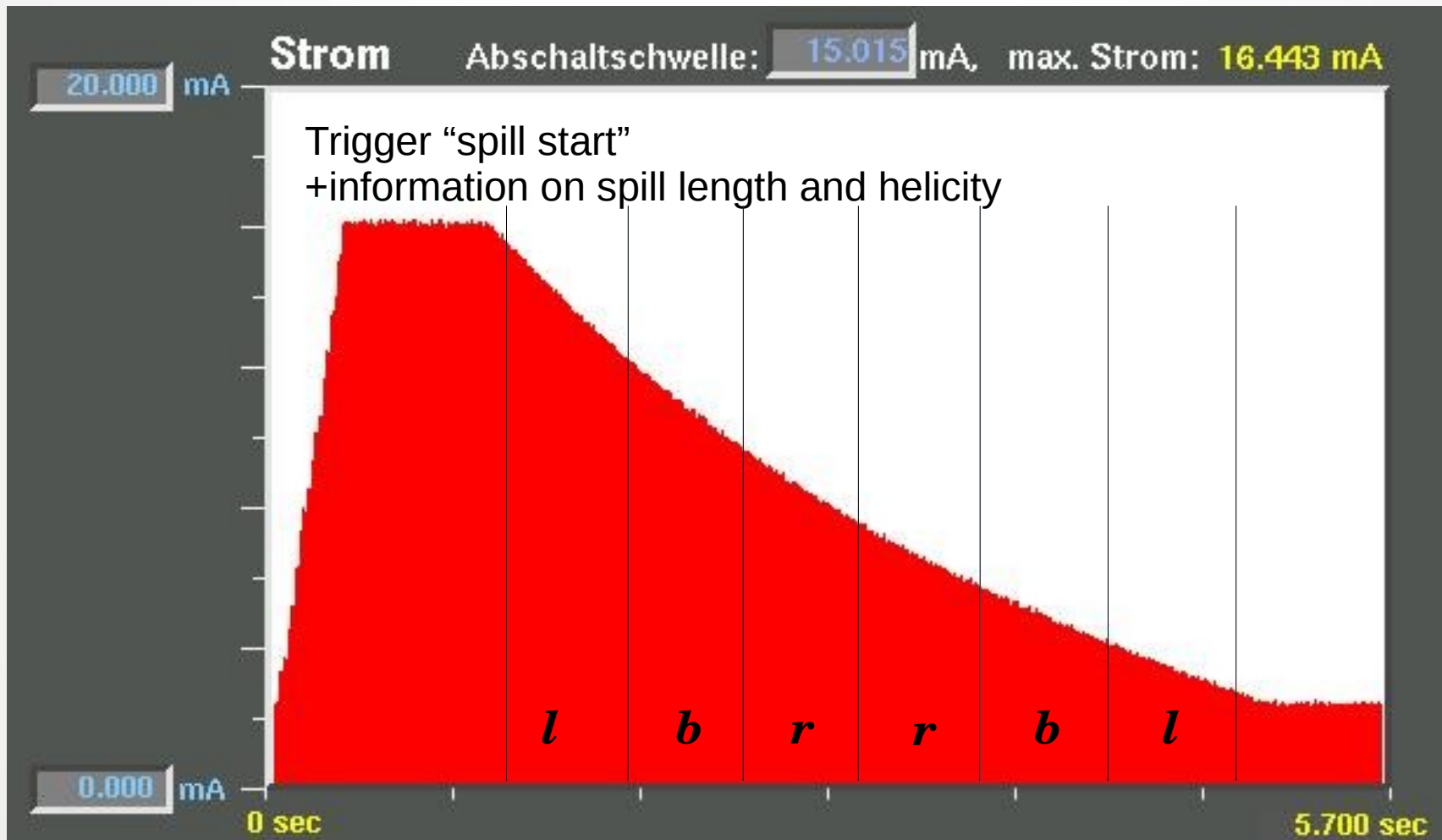
Detector System Considerations

Current vs time in “**Booster Mode**”:



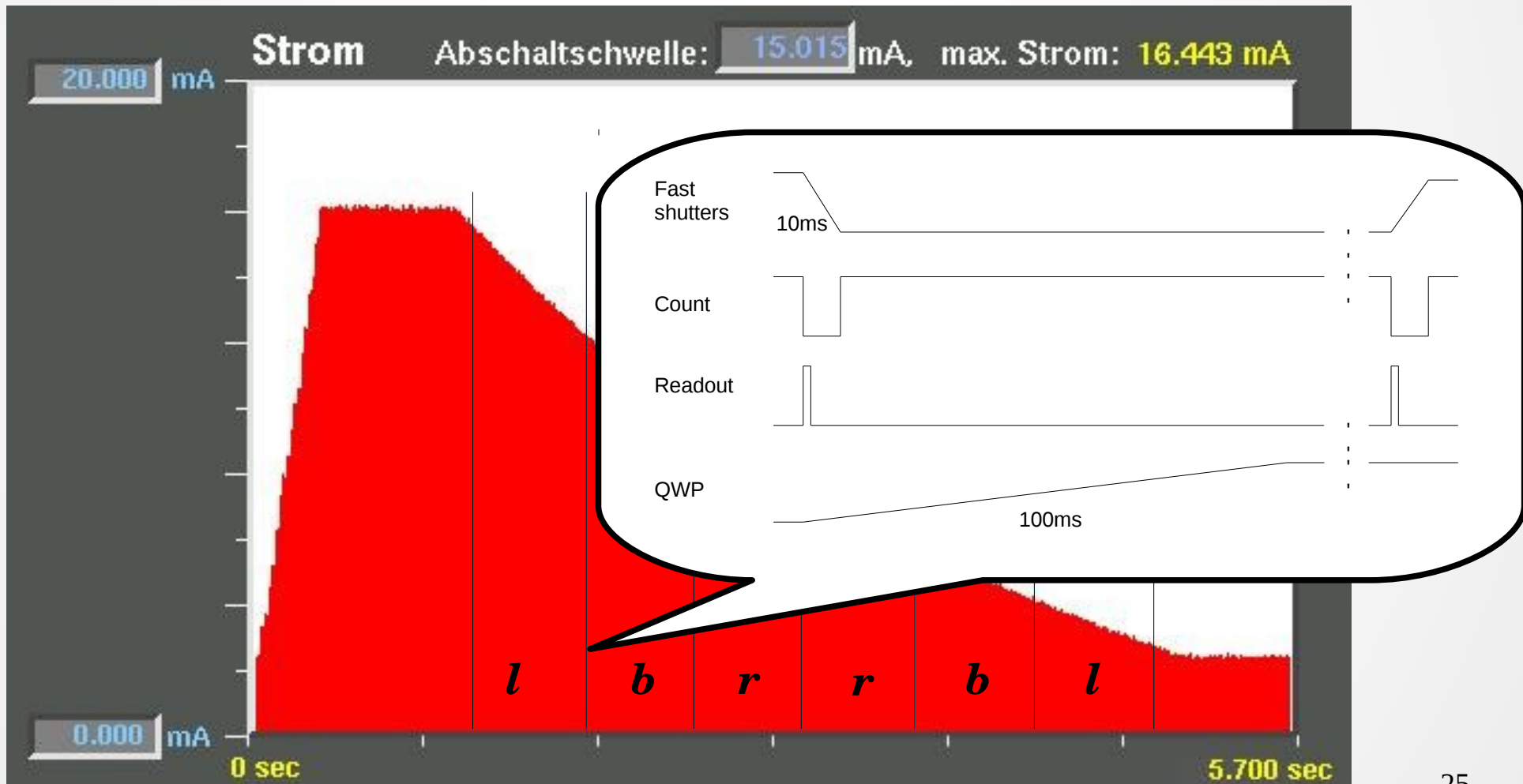
Detector System Considerations

Current vs time in “**Booster Mode**”:



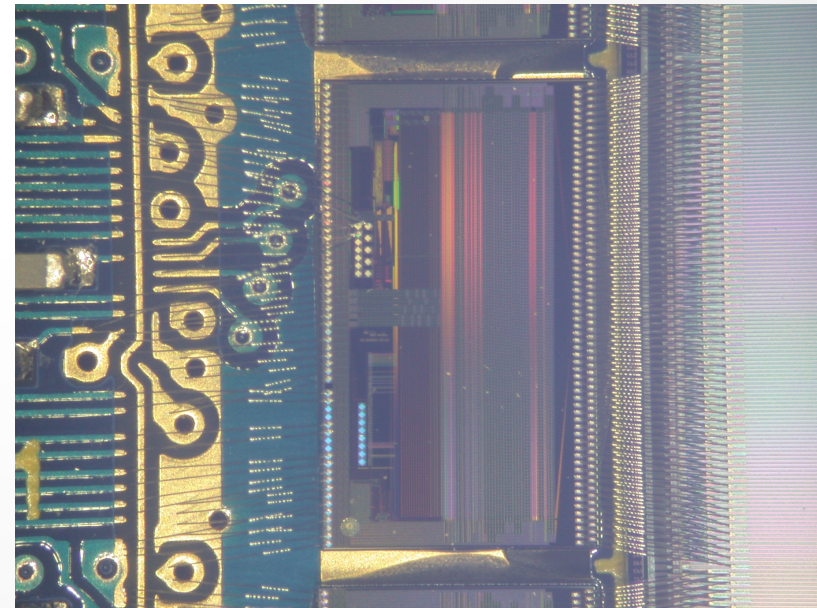
Detector System Considerations

Current vs time in “Booster Mode”:

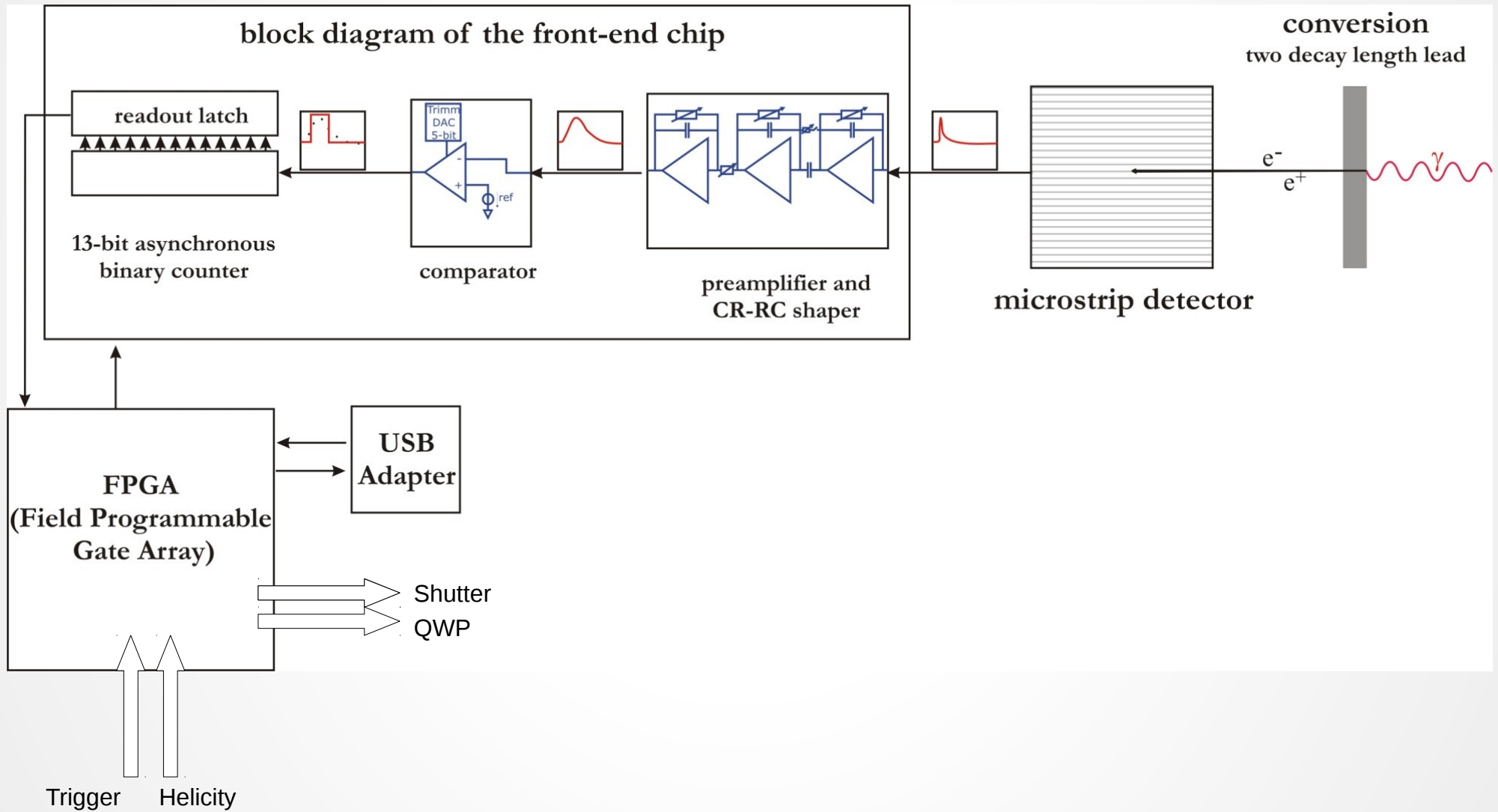


Detector System Considerations

- Minimum of 650 strips
- Rate acceptance of 1 MHz
- FPGA controlled Counting Detector Chips (ASICs)
- TTL output for
 - Fast (10ms) shutters for background measurement
 - Quarter-wave-plates
- TTL input for
 - Spill start
 - Helicity information
 - Veto if current stays below a threshold value



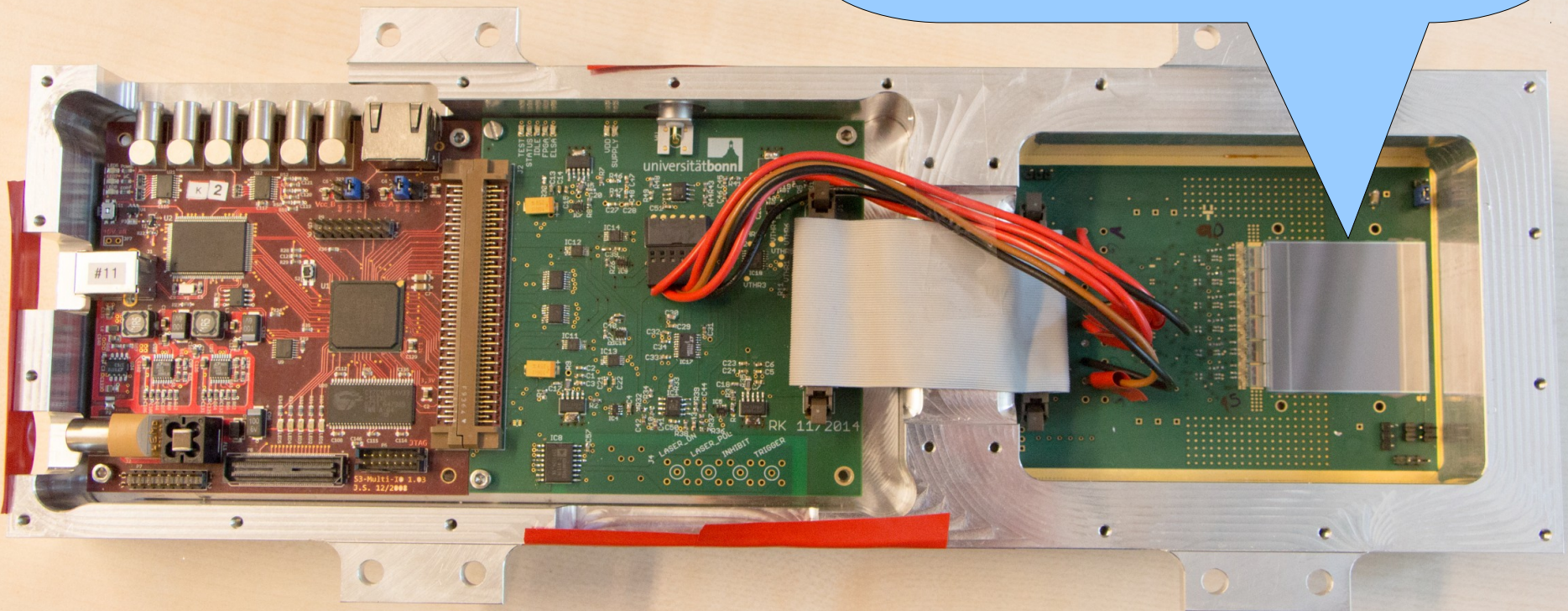
Detector System



Detector System

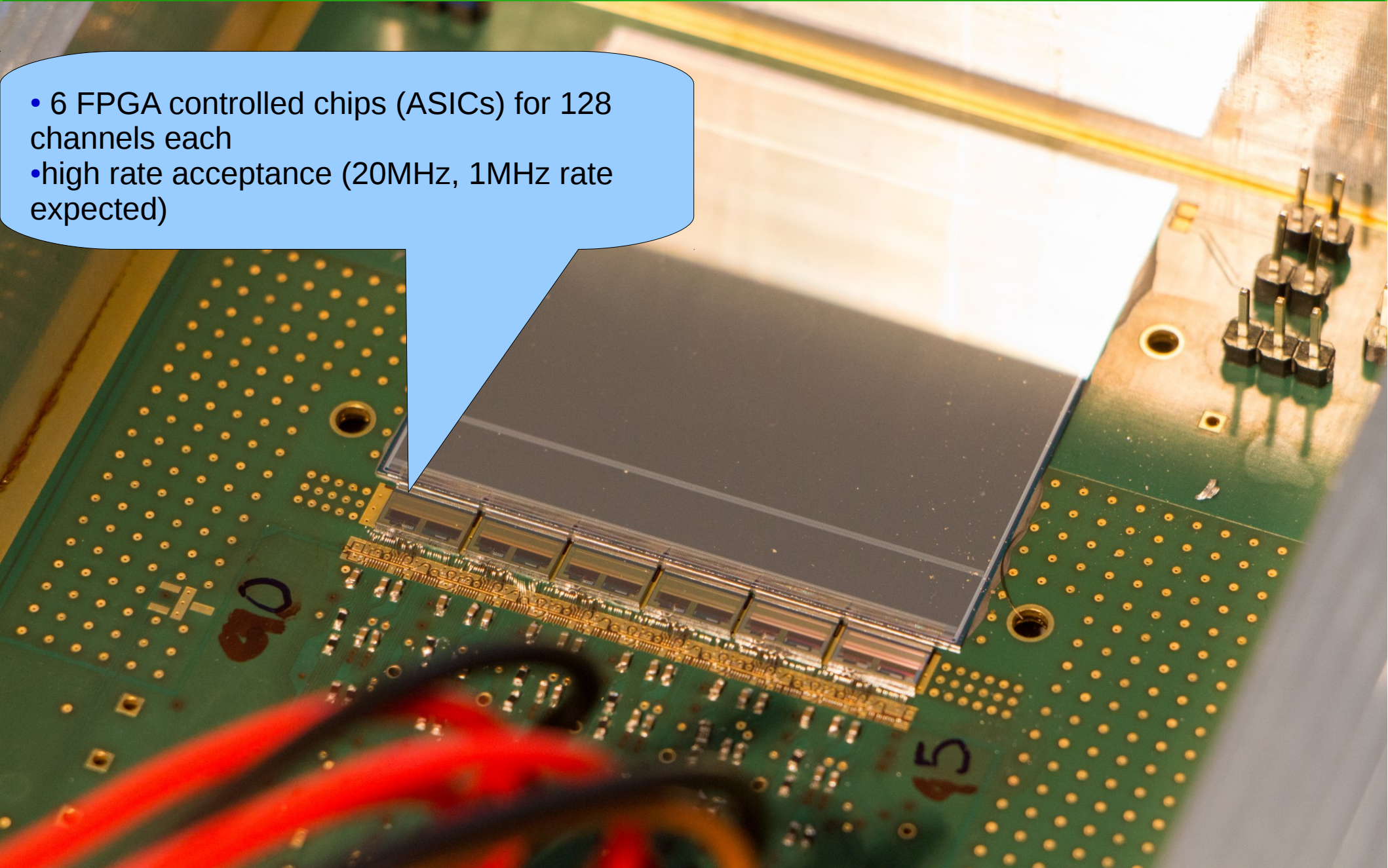
Detector board

- Si, double sided and AC coupled
- 41,3mm x 40mm
- 768 strips with 50 μ m pitch
- Thickness: 300 μ m



Detector System

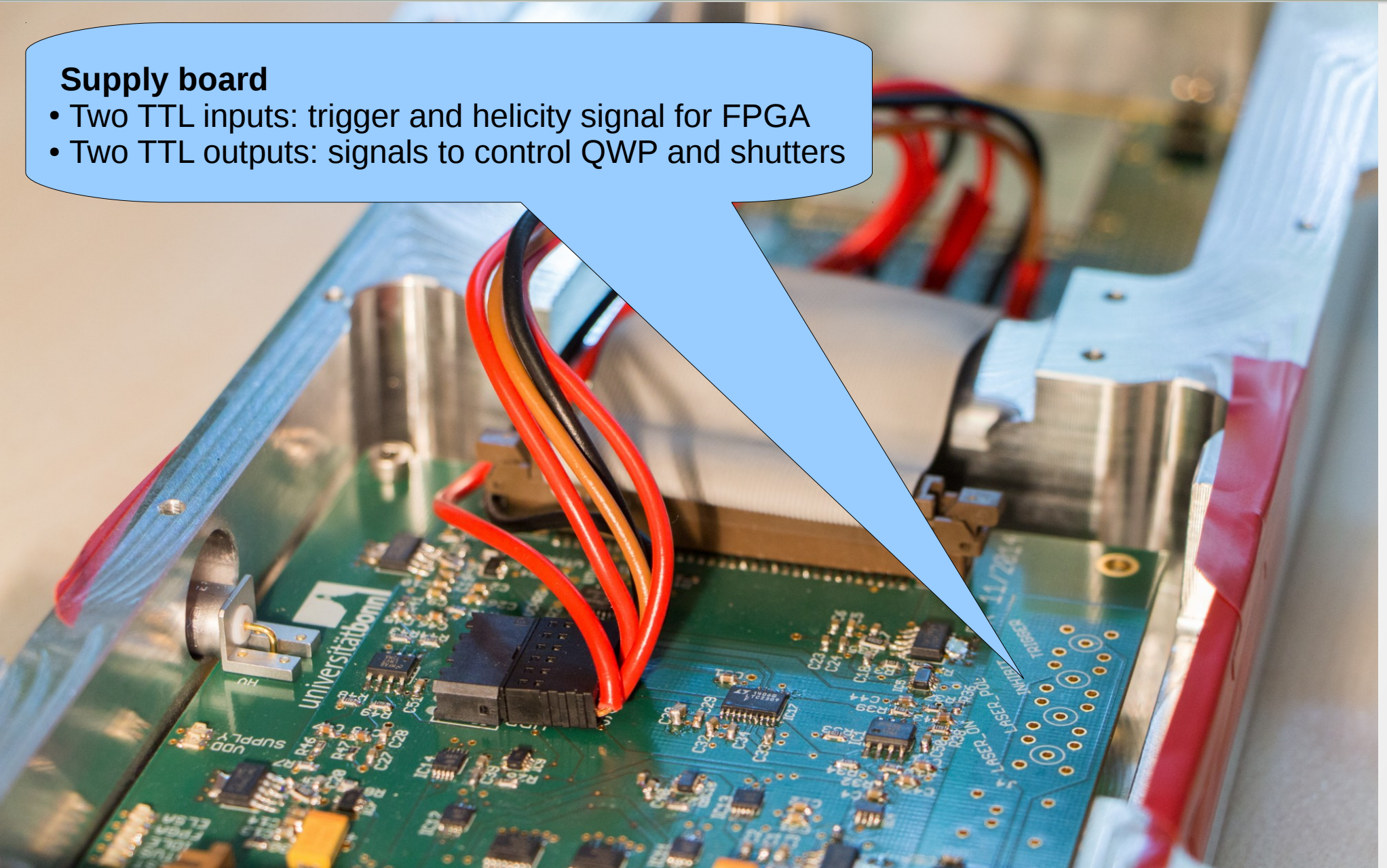
- 6 FPGA controlled chips (ASICs) for 128 channels each
- high rate acceptance (20MHz, 1MHz rate expected)



Detector System

Supply board

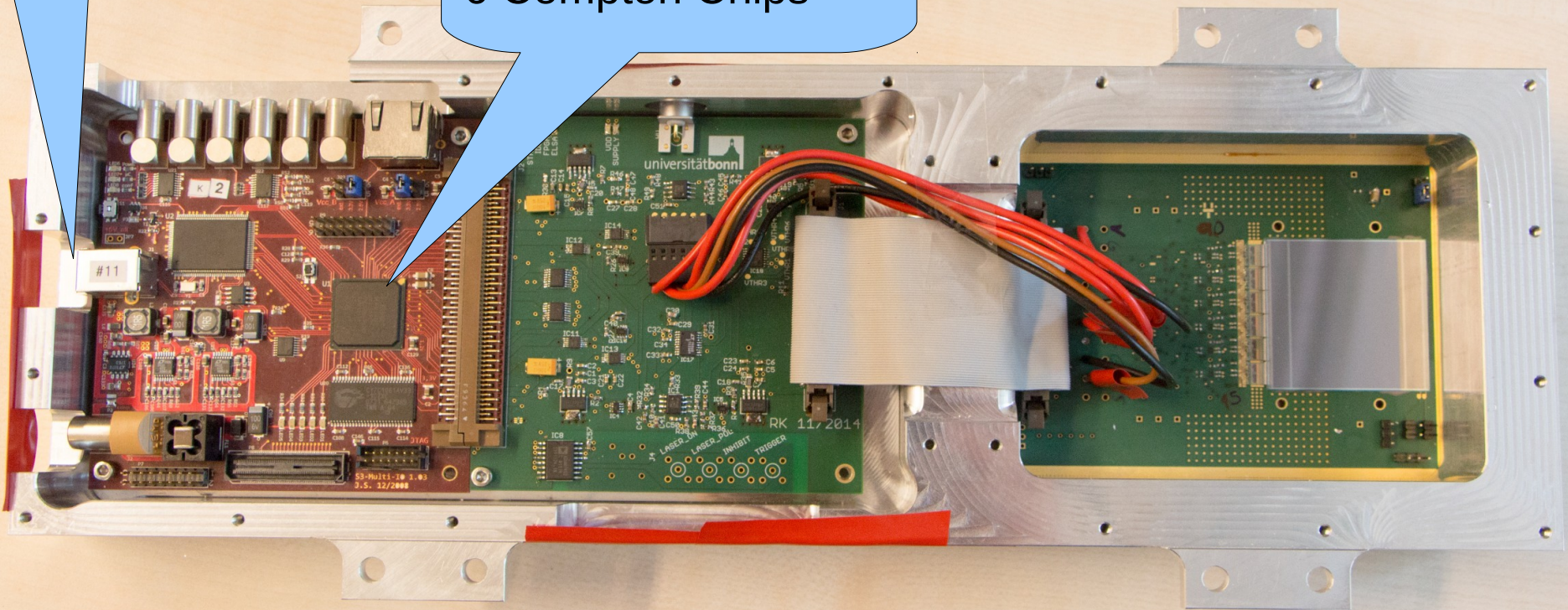
- Two TTL inputs: trigger and helicity signal for FPGA
- Two TTL outputs: signals to control QWP and shutters



Detector System

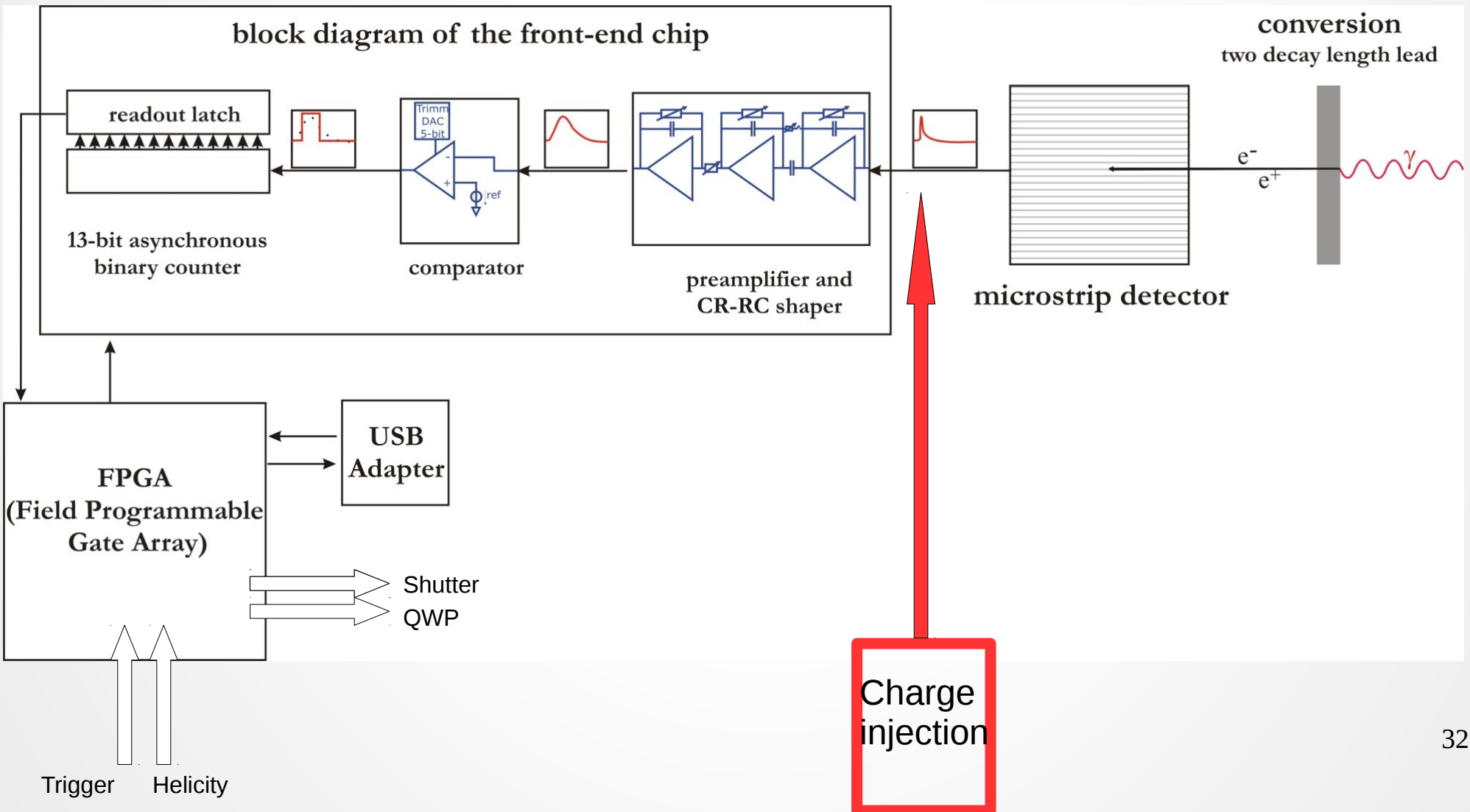
•Readout via usb

•FPGA used to control
6 Compton Chips

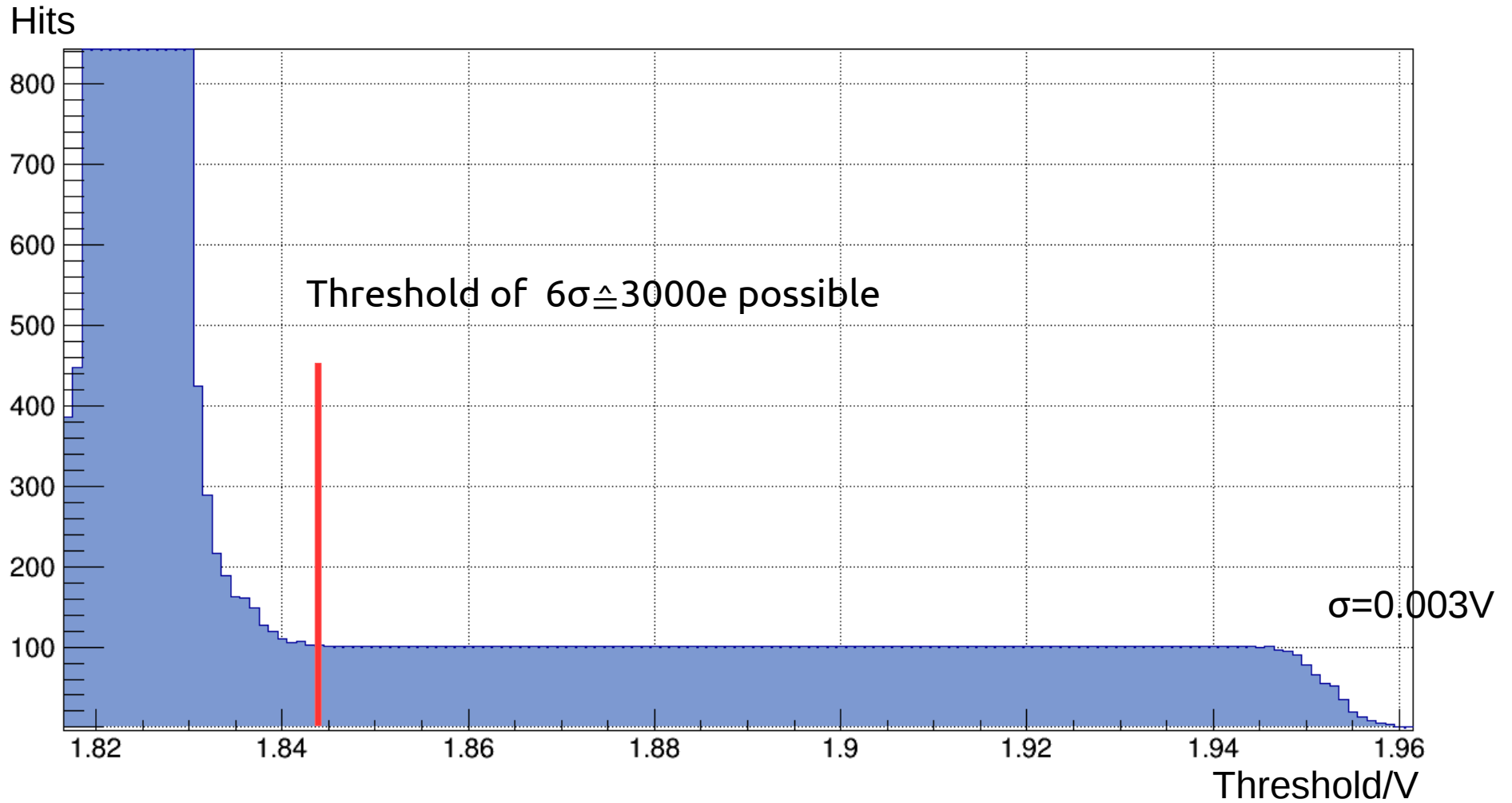


Detector Tests

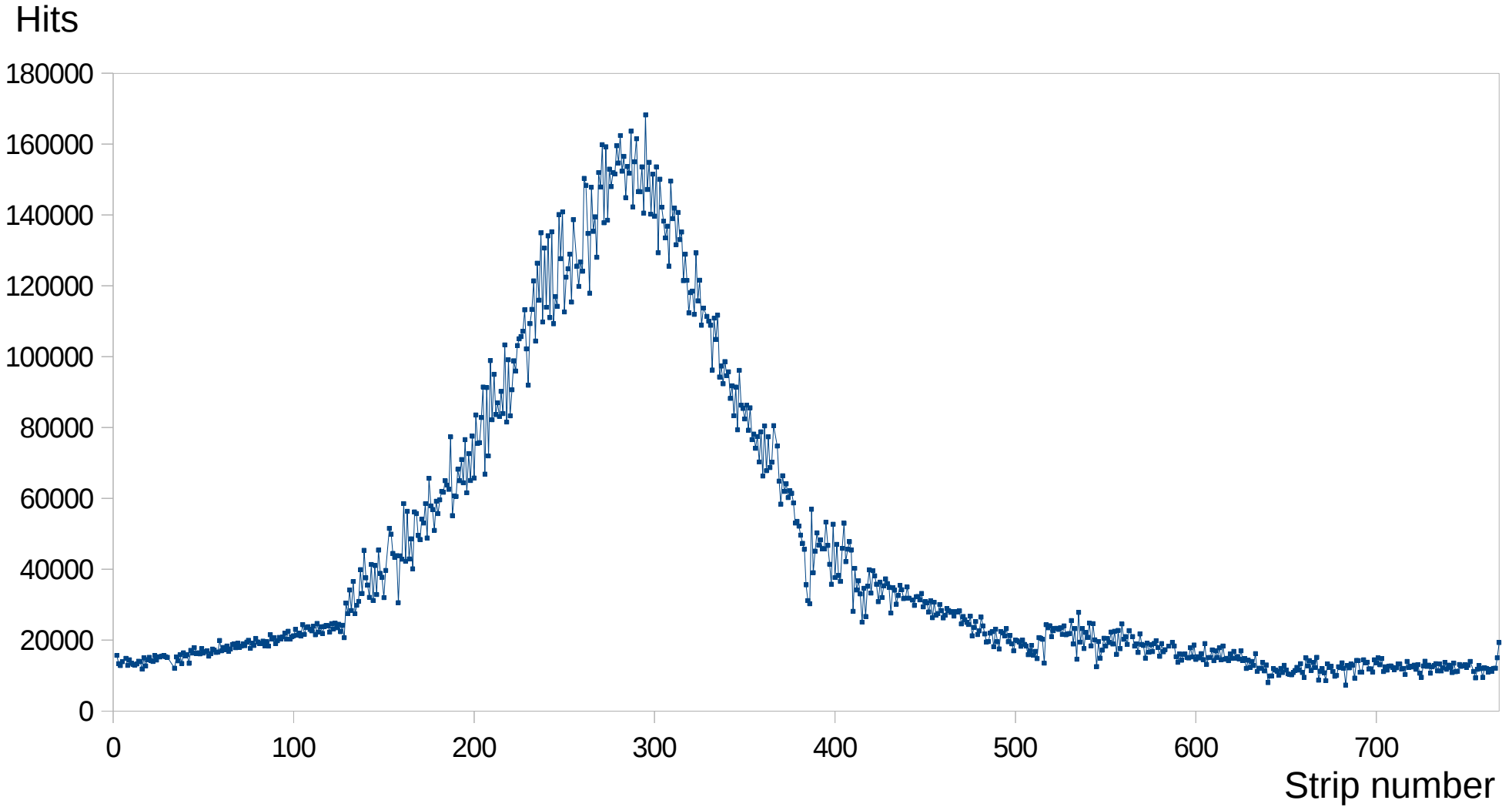
- MIP will generate 24 000 electron-hole pairs in 300 μ m silicon (MPV)
- Charge injection of 100 x 24 000 electrons for a threshold scan:



Detector Tests



Background Measurement with Test Beam



Expected Measuring Time

- Earlier tries:
 - Detector with 100 μ m pitch
 - Laser power 7W
 - High background due to bad vacuum

90 minutes

Expected Measuring Time

- Improvements:
 - Detector with 50 μ m pitch
 - Laser power 20W
 - IGP for better vacuum

5 minutes

Thank you for your attention!